Docket Number: 071469-0303535

Client Reference: RAJ-001

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In set the Application of

NAVID L O'MEARA, et al.

Group Art Unit: 2812

Application No.: 10/630,969

Examiner:

Filed: July 31, 2003

Confirmation No.: 1846

For: FORMATION OF ULTRA-THIN OXIDE LAYERS BY SELF-LIMITING INTERFACIAL

OXIDATION

## INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449s. As this application was filed after June 30, 2003, no copies of the cited U.S. patent or patent publication are attached. However, one copy of each non-patent literature reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

Dale S. Lazar

Registration Number 28872

Date: January 8, 2004

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P.O. Box 10500 McLean, VA 22102

PTO/SB/08a (08-03)
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Complete if Known Application Number 10/630,969 Filing Date 07/31/2003 First Named Inventor DAVID L O'MEARA Art Unit 2812 Examiner Name

(Use as many sheets as necessary) Attorney Docket Number 071469-0303535 of Sheet

	U. S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number  Number-Kind Code <sup>2 (if known)</sup>	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
	1	US- 6,197,641 B1	03-06-2001	HERGENROTHER et al.		
	2	<sup>US-</sup> 6,090,723	07-18-2000	THAKUR et al.		
	3	<sup>US-</sup> 5,817,581	10-06-1998	BAYER et al.		
	4	<sup>US-</sup> 5,334,281	08-02-1994	DOERRE et al.		
	5	US- 5,264,396	11-23-1993	THAKUR et al.		
	6	US- 2001/0031562 A1	10-18-2001	RAAIJMAKERS et al.		
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	FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No.1	Foreign Patent Document  Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
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Signature		Considered	

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stitute for form 1449B/PTO Complete if Known **Application Number** 10/630,969 INFORMATION DISCLOSURE Filing Date 07/31/2003 STATEMENT BY APPLICANT First Named Inventor DAVID L O'MEARA Art Unit 2812 (Use as many sheets as necessary) Examiner Name Attorney Docket Number 071469-0303535 Sheet of

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²		
	A	LIU, H.I. ET AL., "Self limiting oxidation for fabricating sub-5nm silicon nanowires," Appl. Phys. Letter, American Institute of Physics, Vol. 64 (No. 11), p. 1383-1385, (March 11, 1994).			
	В	LIU, H.I. ET AL., "Self-limiting oxidation of Si nanowires," J.Vac. Sc. Technol. B, American Vacuum Society, Vol. 11 (No. 6), p. 2532-2537, (Nov/Dec 1993).			
	С	FUKUDA, HIROSHI ET AL., "Fabrication of silicon nanopillars containing polycrystalline silicon/insulator multilayer structures," Appl. Phys. Lett., American Institute of Physics, Vol. 70 (No. 3), p. 333-335, (January 20, 1997).			
	D	ROY, P.K., "Gate Dielectrics," p. 276-289.			

Examiner	•	Date	
Signature		Considered	

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